This listing of claims will replace all prior versions, and listing of claims in the application:

Listing of Claims:

1. (Previously presented) A device for wafer inspection, which comprises a stage for mounting a wafer thereon for inspection, said stage being displaceable in two directions (X,Y) perpendicular to one another, said stage being air-cushioned and provided with a plurality of air nozzles, at least one valve, at least one electric control unit , said at least one valve connected to said at least one electric control unit, wherein said at least one valve is configured so that normal pressure prevails in said air nozzles when said electric control unit delivers a corresponding signal.

2. (Currently amended) The device as defined in claim 1, wherein the signal is triggered by a ~~drop in potential~~ power outage.

3. (Previously presented) The device as defined in claim 1, wherein the signal is triggered by an emergency shut-down.

4. (Previously presented) The device as defined in claim 1, wherein the signal is triggered by a software failure.

5. (Previously presented) The device as defined in claim 1, comprising a first and a second electric drive means for moving said stage along the two displaceable directions (X, Y).

6. (Currently amended) ~~The device as defined in claim 5, wherein said first and second electric drives comprise at least first and second linear motors.~~ A device for wafer inspection, which comprises a stage for mounting a wafer thereon for inspection, said stage being displaceable in two directions (X,Y) perpendicular to one another by first and second electric drive means comprising at least first and second linear motors, said stage being air-cushioned and provided with a plurality of air nozzles, at least one valve, at least one electric control unit , said at least one valve connected to said at least one electric control unit, wherein said at least one valve is

configured so that normal pressure prevails in said air nozzles when said electric control unit delivers a corresponding signal.

7. (Currently amended) The device as defined in claim 6, wherein parallel to the first linear motor there is disposed at least one first track which cooperates with said plurality of air nozzles, ~~the~~ and compressed air emerging through said air nozzles forming an air bearing for the (X) direction.

8. (Currently amended) The device as defined in claim [[6]] 7 , wherein parallel to the second linear motor there is disposed at least one second track which cooperates with said plurality of air nozzles, the compressed air emerging through said air nozzles forming an air bearing for the (Y) direction.

9. (Currently amended) The device as defined in claim [[1]] 8 , configured so that when said at least one valve is open, normal pressure prevails in the air nozzles so that the stage with said plurality of air nozzles rests on the first and second tracks, wherein the position of said stage occupied during the generation of the signal thus being determined.

10. (Previously presented) The device as defined in claim 1, wherein said stage comprises a receptacle for inspection of the wafer.

11. (Currently amended) The device as defined in claim 6 , wherein said stage comprises housing means for said at least ~~the~~ first and second linear motors, corresponding air nozzles for a first and a second stage element, at least one control unit, air supply lines and electric lines.

12. (Previously presented) The device as defined in claim 1, wherein the at least one valve is provided on the air nozzle.

13. (Previously presented) The device as defined in claim 1, wherein the at least one valve is disposed in at least one air supply line.